

## **MICROELECTRONIC DEVICE HAVING DISPOSABLE SPACER**

### **ABSTRACT**

**[0030]** A method of manufacturing a microelectronic device comprising forming a patterned feature over a substrate and employing a fluorine-containing plasma source to deposit a conformal polymer layer over the patterned feature and the substrate. The polymer layer is etched to expose the patterned feature and a portion of the substrate, thereby forming polymer spacers on opposing sides of the patterned feature.